

Impact of Scaled Technology on Radiation Testing and Hardening

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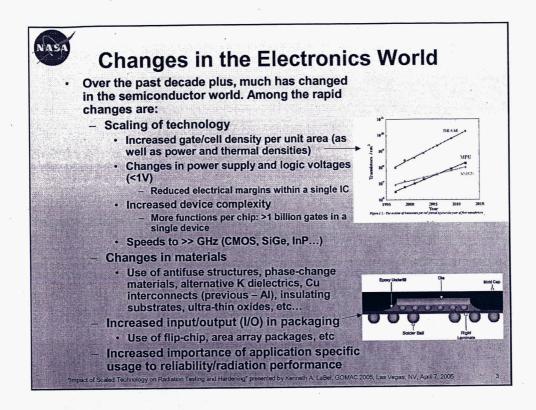
Outline

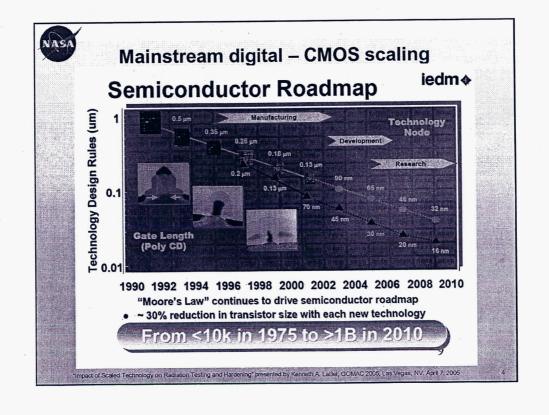
- Emerging Electronics Technologies
 - What has changed and is changing in the commercial semiconductor world
- Effects of Concern
 - Single Event Effects -SEEs
 - Total Ionizing Dose TID
- · Challenges to Radiation Testing and Modeling
 - TID Trends
 - Fault isolation
 - Scaled Geometry
 - Speed
- Summary/Comments

Note: the emphasis of this presentation is digital technologies and SEE.

Some discussion of mitigation implications is included.

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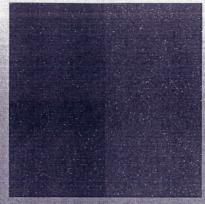






Radiation Effects and Spacecraft

- Critical areas for design in the natural space radiation environment
 - Long-term effects
 - · Total ionizing dose (TID)
 - · Displacement damage
 - Transient or single particle effects (Single event effects or SEE)
 - · Soft or hard errors
- Mission requirements and philosophies vary to ensure mission performance
 - What works for a shuttle mission may not apply to a deep-space mission



An Active Pixel Sensor (APS) imager under irradiation with heavy ions at Texas A&M University Cyclotron

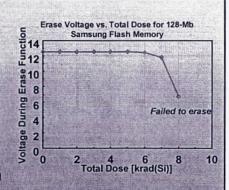
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Total Ionizing Dose (TID)

- Cumulative long term ionizing damage due to protons & electrons
- Effects
 - Threshold Shifts
 - Leakage Current
 - Timing Changes
 - Functional Failures
- Unit of interest is krads(material)
- Can partially mitigate with shielding
 - Low energy protons
 - Electrons

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Displacement Damage (DD)

- Cumulative long term non-ionizing damage due to protons, electrons, applications
- **Effects**
- Production of defects which desults in device degradation
 - May be similar to TID
 - Optocouplers, sola Cells, CCDs, linear bipolar devices 💝
- Unit of interest is particle fluence for each energy mapped to test energy
 - Non-iopting energy loss (NIEL) is one means of discussing
- Shielding has some effect depends on location of device

Reduce significant electron and some proton damage







Single Event Effects (SEEs)

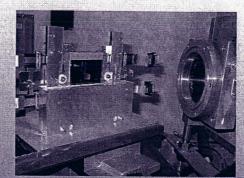
- An SEE is caused by a single charged particle as it passes through a semiconductor material
 - Heavy ions
 - Direct ionization
 - Protons for sensitive devices
 - · Nuclear reactions for standard devices
 - · Optical systems, etc are sensitive to direct ionization
- Effects on electronics
 - If the LET of the particle (or reaction) is greater than the amount of energy or critical charge required, an effect may be seen
 - · Soft errors such as upsets (SEUs) or transients (SETs), or
 - · Hard (destructive) errors such as latchup (SEL), burnout (SEB), or gate rupture (SEGR)
- Severity of effect is dependent on

type of effect system criticality Destructive event in a COTS 120V DC-DC Converter



Typical Ground Sources for Space Radiation Effects Testing

- Issue: TID
 - Co-60 (gamma), X-rays,
 Proton
- Issue: Displacement Damage
 - Proton, neutron, electron (solar cells)
- SEE (GCR)
 - Heavy ions, Cf
- SEE (Protons)
 - Protons (E>10 MeV)
- SEE (atmospheric)
 - Neutrons, protons



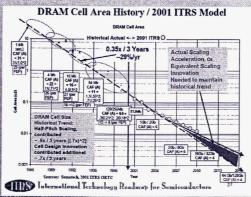
Wide Field Camera 3 E2V 2k x 4k n-CCD in front of Proton Beam at UCDavis

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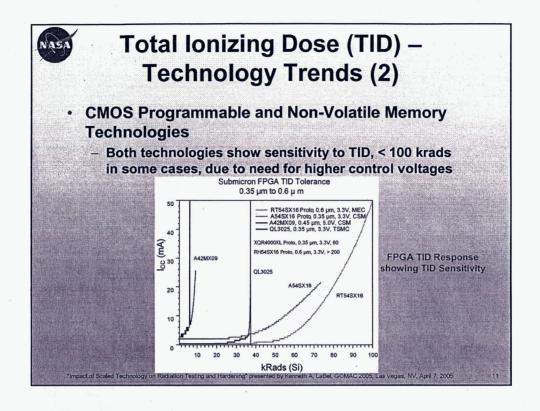


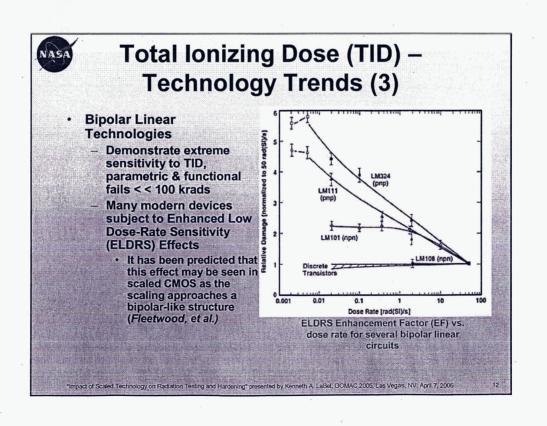
Total lonizing Dose (TID) – Technology Trends (1)

- CMOS Digital Volatile Memory & Logic Technology
 - Present trend to smaller feature size and lower operating voltages indicates a reduced sensitivity to TID effects; e.g. > 100 krad intrinsic capability for 0.25-micron technology and increasing



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Radiation Test Challenge – Fault Isolation

- Issue: understanding what within the device is causing fault or failure. Identification of a sensitive node.
- Technology complications
 - "Unknown" and increased control circuitry (hidden registers, state machines, etc..)
 - Monitoring of external events such as an interrupt to a processor limits understanding of what may have caused the interrupt
 - Example: DRAM
 - » Hits in control areas can cause changes to mode of operation, blocks of errors, changes to refresh, etc...
 - Not all areas in a device are testable

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Chipchip

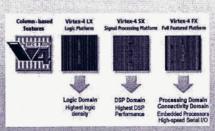
Chipch

Power4 Processor Architecture



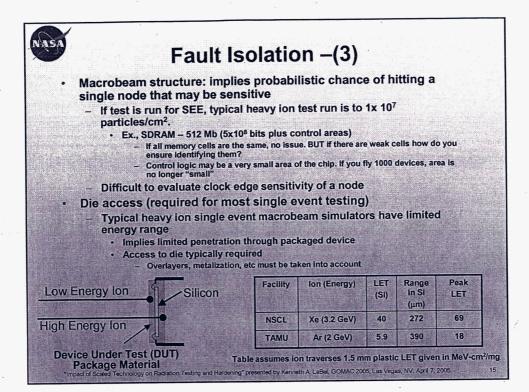
Fault Isolation –(2)

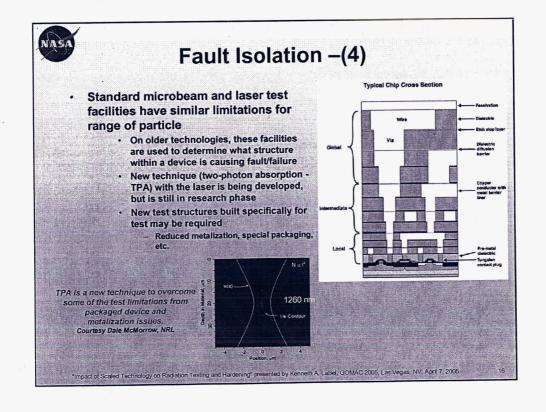
- Example: SRAM-based reprogrammable FPGA- measuring sensitivity of user-defined circuit
 - SEE in configuration area corrupts user circuitry function
 - Can cause halt, continuous misoperation, increased power consumption (bus conflicts), etc.
 - Often the sensitivity of the configuration latches overwhelm user circuitry sensitivity
 - Must have correct configuration to measure user circuit performance
- Increased number of control structures in a device drives an increasing rate of single event functional interrupts (SEFIs)



Complex new FPGA architectures include hard-cores: processing, high-speed I/O, DSPs, programmable logic, and configuration latches

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Radiation Test Challenge - Geometry

- · Issue: the scaling of feature size and closeness of cells
- Technology complications
 - Multiple node hits with a single heavy ion track
 - Because of the closeness of transistors and thinness of the substrate material, a single particle strike can effect multiple nodes potentially defeating hardening schemes.

Litho International Tech Roadmap ledm◆

Lithography Technology Requirements- ITRS 2001 Update

Start Production	2001	2002	2003	2004	2005	2006	2007	2010	2013	2016
Logic Half Pitch (nm)	150nm	130nm	107nm	90nm	80nm	70nm	65nm	45nm	32nm	22nm
Logic Gate in Resist (nm)	90nm	70nm	65nm	53nm	45nm	40nm	35nm	25nm	18nm	13nm
DRAM Half Pitch (nm)	130nm	115nm	100nm	90nm	80nm	70nm	65nm	45nm	32nm	22nm
Contact in Resist (nm)	165nm	140nm	130nm	110nm	100nm	90nm	80nm	55nm	40nm	30nm
Overlay	45nm	40nm	35nm	32nm	28nm	25nm	23nm	18nm	13nm	9nm

Source: ITRS

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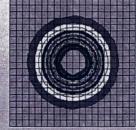
NASA

Geometry Implications (2)

- Multiple node hits (cont'd)
 - Ex., memory array
 - A single particle strike can spread charge to multiple cells. If the cells are logically as well as physically located
 - Standard memory scrub techniques such as Hamming
 - This is not new, simply exacerbated by scaling.
 Traditional SEU modeling considers particle strikes directly on a transistor
 - Charge spreading for strikes near but not on the transistor can generate errors
 - Measured error cross-sections may exceed physical cross-sections
 - Albeit actual individual targets are smaller for a single particle
 - More targets and the spread of non-target hits implied potentially increased error rates per device

The role of particle directionality and of secondaries requires future use of physics-based particle interaction codes coupled with circuit tools.

GEANT4, MCNPX, etc. are the type of codes required
 Efforts begun to turn these into tools and not just science codes



Charge spreading from a single particle in an active pixel sensor (APS) array impacts multiple pixels

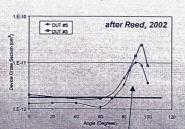
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Geometry Implications (3)

- High-aspect ratio electronics
 - For "standard" devices, the direction of the secondary particles produced from a proton (or neutron) are considered omnidirectional
 - However, for electronics where there is a high-aspect ratio (very thin with long structure), this is not the case
 - The forward spallation of particles when the proton enters the device along the long structure increases the potential error measurement cross-section
 - Test methods and error rate predictions need to consider this



Effects of protons in SOI with varied angular direction of the particle;
Blue line represents expected response with "standard" CMOS devices.

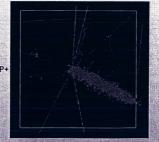
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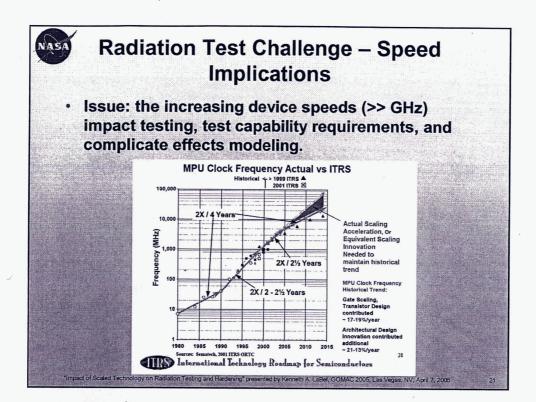
Geometry Implications (4)

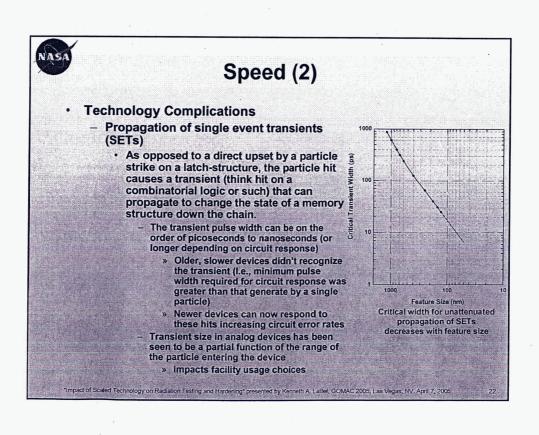
- Ultra-thin oxides provide two concerns
 - Single particles rupturing the gate
 - This is a function of the thinness and the current across a gate oxide
 - The impact of oxide defects
 - Role for TID
- Secondaries from packaging material
 - Even on the ground, particle interaction with packaging materials can cause upsets to a sensitive device
 - Ex., Recent FPGA warning of expectation of up to 1 upset/spontaneous reconfiguration a day!
- Small probability events have increased likelihood of occurring
 - If 1 in a 10⁹ particles causes a "larger" LET event or 1 in 10⁶ transistors can cause a more complex error
 - With billion plus transistor devices and potential use of >1000 of the same device (re: solid state recorders), small probabilities become finite

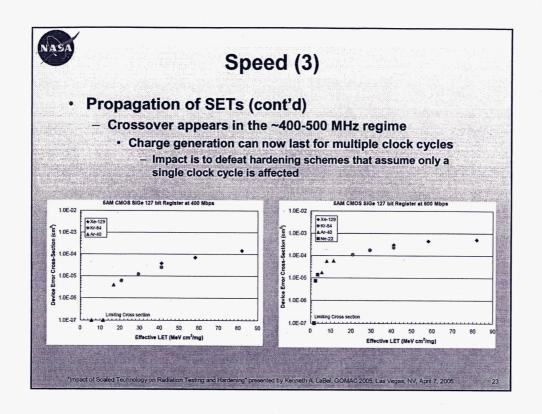


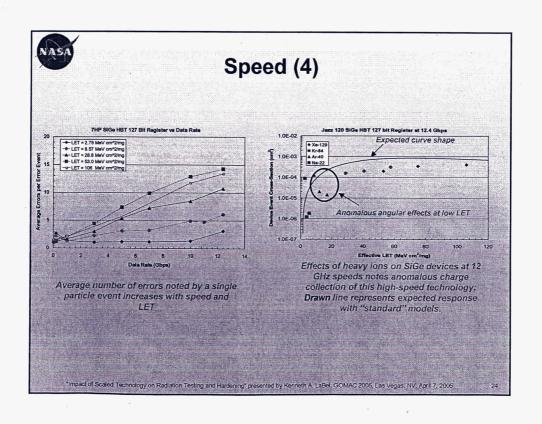
Sample 100 MeV proton reaction in a 5 um Si block. Reactions have a range of types of secondaries and LETs. (after Weller, 2004)

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Speed (5)

Testing at a remote facility requires highly portable test equipment capable of high-speed measurements

- Tester needs to be near the device or utilize high-speed drivers
 - Cable runs between the device under test (DUT) and the tester can be up to 75 feet
- Simple devices like a shift register chain can be tested using bit error rate testers (BERTs)

BERTs can run to ~\$1M and tend to be very sensitive to problems from shipping

At proton test facilities secondaries are generated (neutrons) that can cause failure in the expensive test equipment they are located near the DUT

Self-test techniques for testing devices being developed for shiftregisters

Modern reconfigurable FPGA-based test boards being developed to test more generic devices



Beware of stray neutrons impinging on your test equipment. Here, Borax is shown on top of a power supply to absorb neutrons.

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Speed (6)

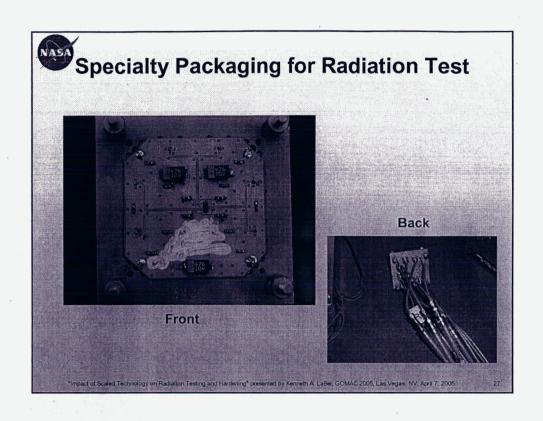
- Testing in a vacuum chamber implies mechanical, power/thermal, and hardware mounting constraints
 - High-speed devices often mean high power consumption
 - Issue is mounting of DUT in vacuum chamber and removal of thermal heat
 - Can also be a challenge NOT in a vacuum DUT may need to be custom packaged to allow for thermal issues
 - Active system required for removal of heat

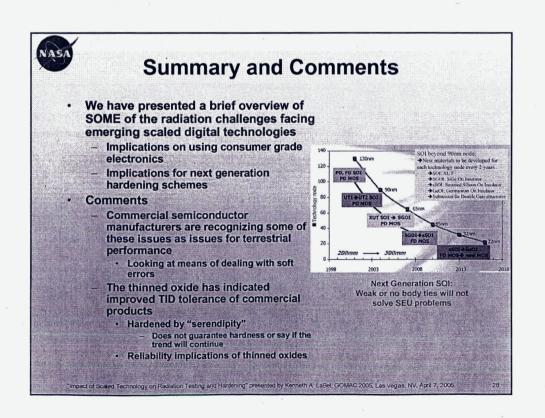
Brookhaven National Laboratories' Single Event Upset Test Facility (SEUTF)

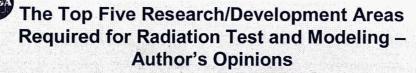


Vacuum Chamber User equipment

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- 5 Understanding extreme value statistics as it applies to radiation particle impacts
- 4 High-Energy SEU Microbeam and TPA Laser
- 3 System Risk Tools
- · 2 Portable High-Speed Device Testers
- 1 Physics Based Modeling Tool

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